

## PRESSURE SENSITIVE ELEMENT

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 EC Classification:  
 Equivalents: JP3143858B2

### Abstract

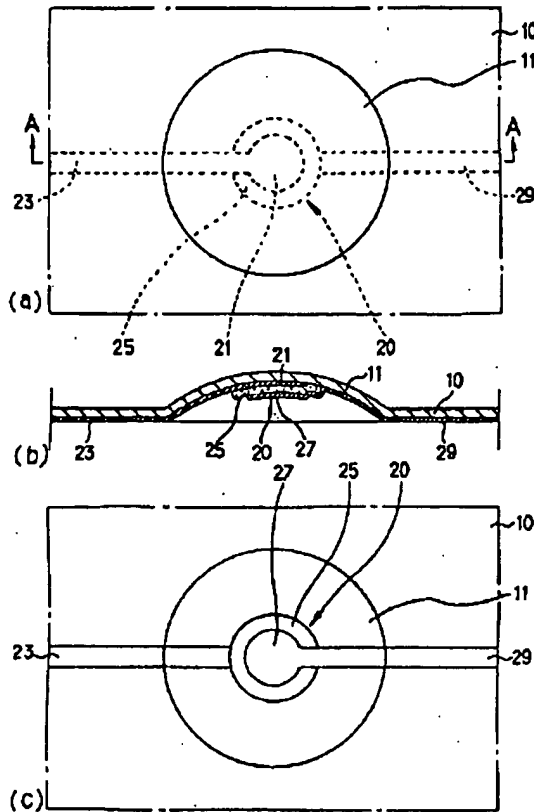
**PROBLEM TO BE SOLVED:** To provide a pressure sensitive element in which thickness is made to be thin, manufacturing is facilitated, and no occurrence of failure resulting from an assembling error is allowed.  
**SOLUTION:** A pressure sensitive element is composed of a pressure sensitive film element 20 formed in the center of the bottom face of the dome-like pushing portion 11 of a film 10. The pressure sensitive film element 20 is composed of an electrode pattern 21 formed on the face of the film 10, a pressure sensitive resistant film 25 formed on the electrode pattern 21, an electrode pattern 27 formed on a location opposite to the electrode pattern 21 on the pressure sensitive resistant film 25.

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25 感圧抵抗膜  
41-4 導電パターン

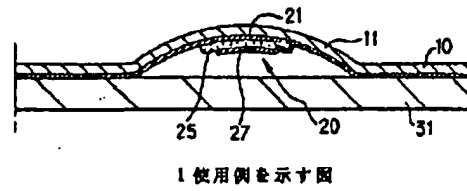
31-5 基板（基材）

【図1】



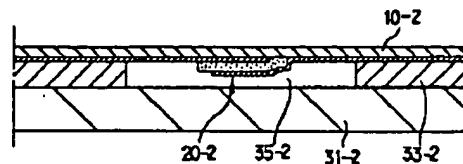
10 フィルム 20 感圧膜素子 21, 27 電極パターン 25 感圧抵抗膜  
本発明の感圧素子を示す図

【図2】



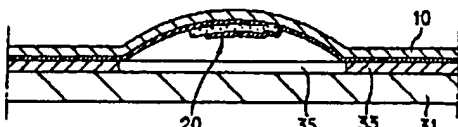
1 使用例を示す図

【図5】



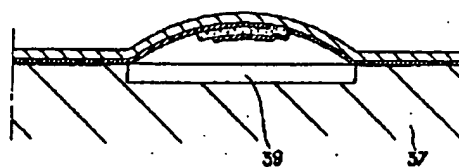
他の感圧素子の1使用例を示す図

【図3】



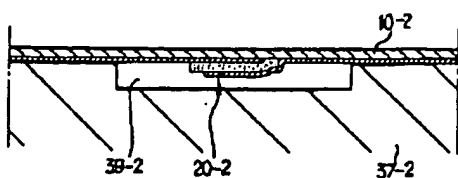
1 使用例を示す図

【図4】



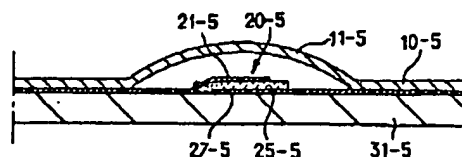
1 使用例を示す図

【図6】



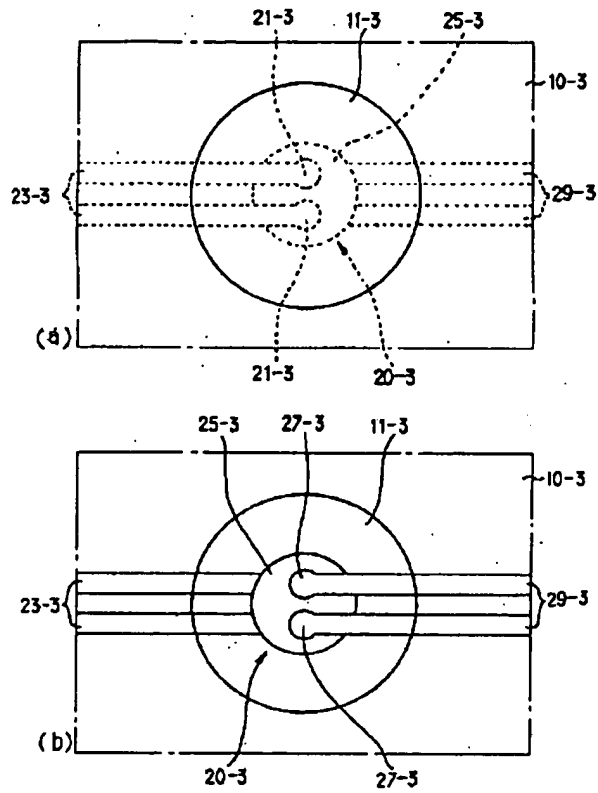
他の感圧素子の1使用例を示す図

【図9】



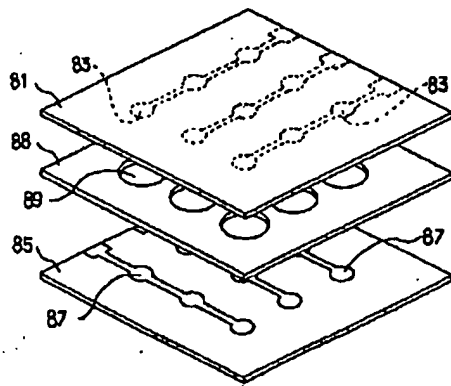
他の感圧素子を示す図

【図7】



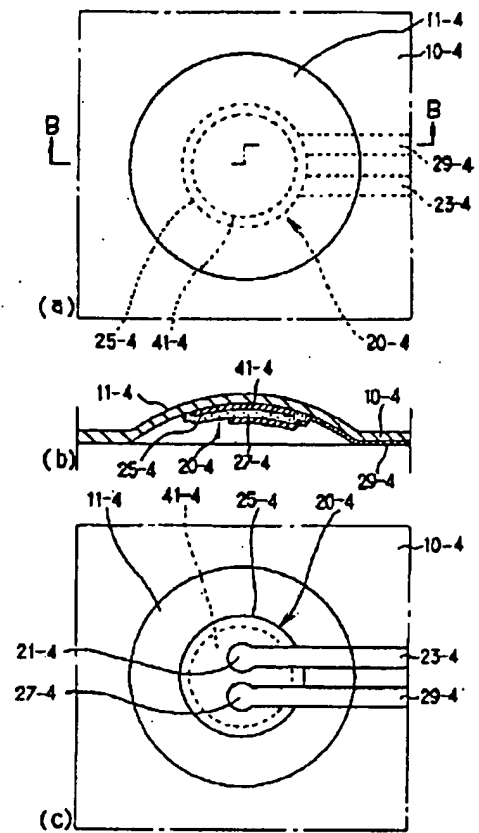
他の感圧素子を示す図

【図10】



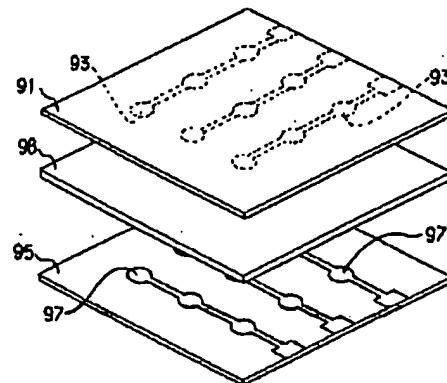
従来のメンブレン型スイッチを示す図

【図8】



他の感圧素子を示す図

【図11】



従来のメンブレン型スイッチを示す図